IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No	
Priority Filing Date	November 24, 1999
Inventor	
Assignee	Honeywell International, Inc.
Priority Group Art Unit	
Examiner	Unknown
Attorney's Docket No.	30-5000-(4015)-Div2
Title: Physical Vapor Deposition Targets	,

PRELIMINARY AMENDMENT

To: Box Patent Application

Assistant Commissioner for Patents

Washington, D.C. 20231

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)

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Sir:

Please enter the following amendments prior to examining the aboveidentified application.

AMENDMENTS

In the Title

Please replace the title with the following: --PHYSICAL VAPOR DEPOSITION TARGETS.--

In The Specification

At page 1 before the "Technical Field" section, please insert the following:

-- RELATED PATENT DATA

This patent resulted from a divisional application of U.S. Patent Application Serial No. 09/449,025, filed November 24, 1999, entitled "Physical

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Vapor Deposition Targets, Conductive Integrated Circuit Metal Alloy Interconnects, Electroplating Anodes, and Metal Alloys For Use as a Conductive Interconnection in an Integrated Circuit", naming Shozo Nagano, Hinrich Hargarter, Jianxing Li and Jane Buehler as inventors, the disclosure of which is incorporated by reference.--

In the Claims

Cancel claims 1-16 and 21-59 without prejudice.

REMARKS

This application is a divisional application of U.S. Patent Application Serial No. 09/449,025. Original claims 1-16 and 21-59 have been canceled without prejudice. Claims 17-20 remain in the application for consideration.

Respectfully submitted,

Dated: 2 - 13 - 01

Mark S. Matkin Reg. No. 32,268